

Si_{1-x}Gex nanocrystals based flash memory

E. M. F. Vieira¹, J. Martín-Sánchez¹, S. Levichev¹, A.G. Rolo¹, M. Buljan³, I. Capan³, A. Parisini⁴, S. Bernstorff⁵, A. Chahboun^{1,2} and M. J. M. Gomes¹

¹ *Physics Department, University of Minho, 4710 - 057 Braga, Portugal*

² *Physics Department, FST Tanger, BP 416 Ziaten, Tanger, Morocco*

³ *Rudjer Boskovic Institute, Bijenicka 54, 10000 Zagreb, Croatia*

⁴ *CNR-IMM Sezione di Bologna, via P. Gobetti 101, 40129 Bologna, Italy*

⁵ *Sincrotrone Trieste, 34149 Basovizza, Italy*

E-mail : chahboun@msn.com

Abstract:

In the last years semiconductor's nanocrystals (NCs) have attracted a strong attention of many researchers mainly due to their size-dependent optoelectronic properties. Si, Ge, and their alloy nanostructures embedded in dielectric matrices have been a subject of huge interest due to their potential applications in nanoelectronics and optoelectronics, as well as floating gate memory structures [1, 2]. The distribution of NCs and their structural properties dramatically affect performance and reliability of NCs based devices. In these frames an investigation of a correlation between structural and electrical properties is an important task.

In this work, we have studied the structural properties of Si_{1-x}Gex NCs embedded in SiO₂ matrix grown by RF-magnetron sputtering technique on Si (100) substrate under different conditions with subsequent post growing annealing in nitrogen atmosphere. The lateral size, shape and distribution of Si_{1-x}Gex NCs in silica matrix were investigated by means of grazing incidence small angle scattering (GISAXS). A mechanism of electronic transport in SiO₂/Si_{1-x}Gex/SiO₂ devices was investigated by current-voltage (I-V) measurements.

Memory effect was shown by capacitance- voltage (C-V) and retention time measurements at low sweeping voltage shift (up to ±3V). We have been able to relate electrical behavior with the structural properties [3 - 5].

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